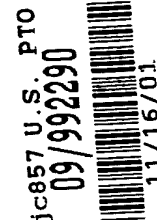


Docket No.: P2000,0282

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : MICHAEL SCHITTENHELM  
Filed : Concurrently herewith  
Title : METHOD OF CALIBRATING A TEST SYSTEM FOR  
SEMICONDUCTOR COMPONENTS, AND TEST SUBSTRATE

5 / IDS  
E. J. Sillio  
4 - 24 - 02



INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner of Patents and Trademarks,  
Washington, D.C. 20231

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

U.S. Patent 6,300,757 B1 (Janssen), dated October 9, 2001;

German published Non-Prosecuted Patent Application DE 198 17 763 A 1 (Janssen et al.), dated November 4, 1999, method to calibrate a measuring device;

German published Non-Prosecuted Patent Application DE 199 52 943 A 1 (Kund), dated June 13, 2001, probe card adjustment device for the planarization of probe sets of a probe card;

European Patent Application EP 1 098 200 A2 (Kund), dated May 9, 2001, probe card adjustment device for the planarization of probe sets of a probe card,  
(corresponds to German published Non-Prosecuted Patent Application DE 199 52 943 A 1 above);

U.K. Patent Application GB 2 184 849 A (Eddison et al.), dated July 1, 1987;

If no translation of pertinent portions of any foreign language patents or publications mentioned above is included with the aforementioned copies of those applications, patents and/or publications, it is because no existing translation is readily available to the applicant.

Respectfully submitted,



For Applicants

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Date: November 16, 2001

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